Docket No.:

004066 USA/Consilium/Consilium

PATENT/OFFICIAL

## IN THE UNITED STATES PATENT AND PRACTICAL PROPERTY OF THE PROP

In re Application of

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John F. ARACKAPARAMBIL et al.

OCT 1 4 2004

Serial No. 09/363,966

Group Art Unit: 2125

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**Technology Center 2100** 

Filed: July 29, 1999

Examiner: Steven R. Garland

For:

COMPUTER INTEGRATED MANUFACTURING TECHNIQUES

## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This submission does not constitute a representation that a search has been made or that no better art exists and does not constitute an admission or representation that any of the listed documents is material or constitutes prior art. If it should be determined that any of the listed documents does not constitute prior art under the United States law, Applicants reserve the right to present to the Office the relevant facts and law regarding the appropriate status of such document.

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## Serial No. 09/363,966

Please charge the fee of \$180.00 under 37 CFR 1.17(p) to Deposit Account No. 08-0219. The Commissioner is also authorized to charge any deficiency in any fees pursuant to 37 CFR § 1.17 associated with this communication and to credit any excess payment to Deposit Account No. 08-0219.

Respectfully submitted,

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Date: 0/5/04

SHEET 1 OF 2

| INFORMATION DISCLOSURE CITATION IN AN APPLICATION TO BE  (PTO-1449)  (PTO-1449)  (PTO-1449)  (PTO-1449)  (PTO-1449) |              |          |                  | ATTY. DOCKET NO. 004066 USA/ Consilium/Consilium  RECEIVED  OCT 1 4 2004  Technology Center 2100  APPLICANT John F. ARACKAPARAMBIL et al.  FILING DATE July 29, 1999  GROUP 2125 |          | 2004   |                |
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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